

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATO, et al.
Serial No.: 09/766,596
Filed: January 23, 2001
For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR

SUPPLEMENTAL PRELIMINARY AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

May 29, 2001

Sir:

Prior to examination of the above-identified application, and supplementing the Preliminary Amendment filed January 23, 2001, please amend the above-identified application as follows:

IN THE CLAIMS

✓
Please cancel claims 1-26 without prejudice or disclaimer, and add the following new claims to the application:

Sub C1
27. ~~A conveyor system for processing substrates in~~
plural vacuum processing chambers, the conveyor system
including:

1.
a loader;
a vacuum loader; and
double lock chambers, having a loader side and a
vacuum loader side, and having a gate valve for said loader
side and another gate valve for said vacuum loader side,